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Interaction of slow (<5 keV/u), highly charged ions with nanostructured membranes

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Author

Schenkel, T.

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Interaction of slow (<5 keV/u), highly charged ions with nanostructured membranes

A. Persaud, S. J. Park, J. Nielsson, D. H. Schneider, and T. Schenkel

We report on studies of the interaction of slow, multiply (e. g. Ar3+) and highly charged ions (e. g. Xe44+) with silicon nitride membranes [1]. Arrays of holes are formed in thin (30 to 200 nm thick) membranes by focused ion beam drilling. Aspect ratios of holes range from 1:1 to about 5:1. Charge exchange in thin membranes is investigated as well as energy loss and foil lifetimes under ion beam exposure. We will discuss the question of capillary beam guiding [2] for high ion charge states.

Reference:

- [1] T. Schenkel et al., SPIE V 4656, 10 (2002), J. Vac. Sci. Technol. B in press (2002)
- [2] N. Stolterfoht, et al., Phys. Rev. Lett. 88, 133201 (2002)

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